

Search strategies for Case No. 10005637  
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20/03

Ex. Andre' Stevenson

5430548 ) and (rotate\$2 or rotation\$2 or  
rotating\$4) and mirror\$2

USPT  
5430548

USPT  
((5798831) ) and (rotate\$2 or rotation\$2 or  
rotating\$4) and mirror\$2

USPT  
(5680207 ) and (rotate\$2 or rotation\$2 or  
rotating\$4) and mirror\$2

USPT  
(5680207 ) and (rotate\$2 or rotation\$2 or  
rotating\$4)

USPT  
5680207

USPT  
(((5680207 ) and matrix\$2 and (light\$2 or  
optical) near (detection or detect\$2 or beam\$2)  
and linear\$2 near pattern\$2) )and (scan\$2 or  
scanning) and mirror\$2 ) and (rotate\$2 or  
rotation\$2 or rotating\$4)

USPT  
(((5798831) )and (scan\$2 or scanning) and  
mirror\$2 ) and (rotate\$2 or rotation\$2 or  
rotating\$4)

USPT  
((5798831) ) and (scan\$2 or scanning) and  
mirror\$2

USPT  
(((5680207 ) and matrix\$2 and (light\$2 or  
optical) near (detection or detect\$2 or beam\$2)  
and linear\$2 near pattern\$2) ) and (scan\$2 or  
scanning) and mirror\$2

USPT  
((6487307) ) and (scan\$2 or scanning) and  
mirror\$2

USPT  
(6487307 ) and defect\$2 and image\$2 and  
pattern\$2

USPT  
(6487307 ) and defect\$2

USPT  
6487307

USPT  
(6487307 ) and defect\$2 and (light\$2 or optical)  
near (detection or detect\$2 or beam\$2) and  
(scan\$2 or scanning)and image\$2 and pattern\$2  
and linear\$2 near pattern\$2 and matrix\$2

USPT  
6487307

USPT  
(Semiconductor\$2 and defect\$2 and (light\$2 or  
optical) near (detection or detect\$2 or beam\$2)  
and (scan\$2 or scanning)and image\$2 and  
pattern\$2 and linear\$2 near pattern\$2 and  
matrix\$2 ) and light\$2 near beam\$2

USPT  
(Semiconductor\$2 and defect\$2 and (light\$2 or  
optical) near (detection or detect\$2 or beam\$2)  
and (scan\$2 or scanning)and image\$2 and  
pattern\$2 and linear\$2 near pattern\$2 and  
matrix\$2 ) and light\$2

USPT  
Semiconductor\$2 and defect\$2 and (light\$2 or  
optical) near (detection or detect\$2 or beam\$2)  
and (scan\$2 or scanning)and image\$2 and  
pattern\$2 and linear\$2 near pattern\$2 and  
matrix\$2

USPT  
(((5430548 )and (second\$2 or two or  
additional\$2) near (patteren\$2 or wafer\$2 or  
work\$2) )and defect\$2 ) and (second\$2 or two or  
additional\$2)

USPT  
(((5798831 )and matrix\$2 and (light\$2 or  
optical) near (detection or detect\$2 or beam\$2)  
and linear\$2 near pattern\$2 )and defect\$2 ) and  
(second\$2 or two or additional\$2)

USPT  
(((5680207 )and matrix\$2 and (light\$2 or  
optical) near (detection or detect\$2 or beam\$2)  
and linear\$2 near pattern\$2 )and defect\$2) and  
(second\$2 or two or additional\$2)

USPT

((5430548 )and (second\$2 or two or additional\$2) near (patteren\$2 or wafer\$2 or work\$2) ) and defect\$2

USPT  
5680207

USPT  
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USPT  
((((Semiconductor\$2 and defect\$2 near inspection\$2 )and (light\$2 or optical) near (detection or detect\$2 or beam\$2) )and (scan\$2 or scanning) )and image\$2 and pattern\$2 )and linear\$2 near pattern\$2 ) and matrix\$2)

USPT  
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5430548

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USPT  
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USPT  
5798831

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((((Semiconductor\$2 and defect\$2 near  
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(detection or detect\$2 or beam\$2) )and (scan\$2  
or scanning) ) image\$2 and pattern\$2

USPT

((((Semiconductor\$2 and defect\$2 near  
inspection\$2 )and (light\$2 or optical) near  
(detection or detect\$2 or beam\$2) )and (scan\$2  
or scanning) ) image

USPT

((Semiconductor\$2 and defect\$2 near  
inspection\$2 )and (light\$2 or optical) near  
(detection or detect\$2 or beam\$2) ) and (scan\$2  
or scanning)

USPT

(Semiconductor\$2 and defect\$2 near  
inspection\$2 ) and (light\$2 or optical) near  
(detection or detect\$2 or beam\$2)

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Semiconductor\$2 and  
defect\$2 near inspection\$2